

Contents

<i>Preface</i>	<i>xi</i>
<i>Contributors</i>	<i>xv</i>
<i>Future Contributions</i>	<i>xvii</i>
1. The Work of Albert Victor Crewe on the Scanning Transmission Electron Microscope and Related Topics	1
<i>A. V. Crewe</i>	
1. Introduction	2
2. Some Chicago Aberrations: A Personal Collection	6
Acknowledgments	13
3. Electron Microscope Studies: Achievements of the Crewe Lab	13
Introduction	14
Construction (Reference Group A)	16
Source Development (Reference Group B)	17
STEM Development and Atomic Images (Reference Group C)	18
The Field Emission SEM (Reference Group D)	19
Energy Loss and Radiation Damage (Reference Group E)	20
Secondary Electron Production (Reference Group F)	21
DNA Labeling (Reference Group G)	21
Nucleosomes (Reference Group H)	22
Attempts at Aberration Correction (Reference Group I)	23
Theoretical Electron Optics (Reference Group J)	27
Optimization and the Super-High-Resolution SEM (Reference Group K)	28
Image Processing (Reference Group L)	30
Three-Dimensional Reconstruction (Reference Group M)	31
Hemoglobin Work (Reference Group N)	32
References (of Chicago Aberrations)	37
References (of DOE Report)	38
2. A Review of the Cold-Field Electron Cathode	63
<i>L. W. Swanson and G. A. Schwind</i>	
1. Introduction	63
2. Work Function	65

3. Energy Distribution	67	5.2. Bright-Field Images Obtained with 50-kV CFE-STEM	142
3.1. Theoretical Background	67	5.3. Single-Atom Observation	144
3.2. Analytical versus Numerical Results	68	5.4. Development of the Electron Energy-Loss Spectrometer	147
3.3. Measured Values of the FWHM for the Tungsten Cold-Field Electron	72	5.5. Further Development of 50-kV CFE-STEM	149
4. Source Optics	79	6. Hitachi's First Commercialized Dedicated STEM (by Takahito Hashimoto)	150
5. Column Optics Using the Cold-Field Electron Source	82	6.1. 200-kV Analytical CFE-TEM, HF-2000	150
6. Current Stability	86	6.2. "Gate Viewer," Trigger for Dedicated STEM	154
6.1. High-Frequency Current Fluctuations	87	6.3. Novel Functions for HD Series	161
6.2. Long-Term Current Drift	88	7. Cutting-Edge Applications with Customized HD Models (by Toshie Yaguchi)	165
6.3. Cold-Field Electron End-of-Life Mechanisms	94	7.1. 120-kV FE UHV for Nanotubes	165
7. Summary	97	7.2. 200-kV FE Ultrahigh-Resolution STEM	165
Acknowledgments	98	7.3. 3D Structural and Elemental Analysis	169
References	98	8. Aberration-Corrected CFE-STEM (by Kuniyasu Nakamura)	170
3. History of the STEM at Brookhaven National Laboratory	101	8.1. Atomic-Level Characterization Instrument	170
<i>Joseph S. Wall, Martha N. Simon, and James F. Hainfeld</i>		8.2. Theoretical Consideration of Advantages of Aberration-Corrected CFE-STEM	172
1. Introduction	101	8.3. Evaluation of Aberration-Corrected CFE-STEM	173
2. Instrument Design Parameters	102	8.4. Advanced Application Results with HD-2700C	176
3. Heavy Metal Cluster Labeling	106	9. Conclusion and Future Prospective (by Hiroshi Kakibayashi)	181
4. Early User/Collaborator Projects	108	Acknowledgments	182
5. Recent Work	115	References	182
6. Conclusion	115	5. Two Commercial STEMs: The Siemens ST100F and the AEI STEM-1	187
Acknowledgments	115	<i>P. W. Hawkes</i>	
References	116	1. Introduction	188
4. Hitachi's Development of Cold-Field Emission Scanning Transmission Electron Microscopes	123	2. The AEI STEM-1	188
<i>Hiromi Inada, Hiroshi Kakibayashi, Shigeto Isakozawa, Takahito Hashimoto, Toshie Yaguchi, and Kuniyasu Nakamura</i>		3. The Siemens ST100F	191
1. Introduction	124	3.1. The New ELMISKOP ST100F Scanning Transmission Electron Microscope	195
2. The Dawn of Hitachi Electron Microscopes (by Hiromi Inada)	125	Introduction	195
2.1. Crewe STEM Shock and Field Emission Development	125	Construction of the ELMISKOP ST100F	195
3. Cold FE-SEM Studies and Expansion to Different Fields	128	Advantages of the Scanning Transmission Electron Microscope	198
3.1. CFE-STEM Development at HCRL	128	Imaging with Low Radiation Damage	198
3.2. CFE-SEM Development at Naka Works	131	Conclusion	201
3.3. Studies of Field Emission Stability	132	3.2. Image Forming Systems	203
4. Expansion of High-Voltage TEMs and STEMs	137	General Remarks	203
4.1. Holography Studies by Tonomura with FE-TEMs	137	The Imaging Process	204
4.2. Multistage Acceleration CFEG for TEM Applications	138	Image Forming Properties of Magnetic Lenses	205
4.3. Commercialized Analytical CFE-TEM/STEM	139	Strong Lenses	208
5. Development of 50-kV STEM in 1970s (by Shigeto Isakozawa)	141	Lens Systems for CTEM and STEM: Similarities and Differences	210
5.1. Development of Hitachi's 50kV Prototype CFE-STEM	141	Requirements for Analytical Microscopy	215
	141	Acknowledgments	217
		References	217

6. A History of Vacuum Generators' 100-kV Scanning Transmission Electron Microscope

221

Ian R. M. Wardell and Peter E. Bovey

1. The Early Days 222
2. Design Considerations for a Commercial STEM 224
 - 2.1. The Objective Lens 225
 - 2.2. The Specimen Stage 226
 - 2.3. The Electron Gun 226
 - 2.4. Location of Analytical Facilities 227
 - 2.5. The Resultant Assembly 227
3. The First STEMs and HB5 Development 232
 - 3.1. The Optical Column 238
 - 3.2. Stage Development 240
 - 3.3. Early Airlock and Manipulator 241
 - 3.4. The Dark-Field Detector 245
 - 3.5. Secondary Electron Detector 246
 - 3.6. Diffraction Facilities 249
 - 3.7. The Energy Analyzer Mk1 251
 - 3.8. Electronics 254
4. Improved Resolution 254
 - 4.1. The MIT HB5 255
 - 4.2. The University of Illinois HB5 256
5. Other Developments 256
 - 5.1. Beam-Blanking Plates 257
 - 5.2. Detectors and the Virtual Objective Aperture 261
 - 5.3. Stage Motor Drives 262
 - 5.4. New Airlock 264
 - 5.5. Energy Analyzer Mk2 266
 - 5.6. Gun Lens 266
 - 5.7. High-Excitation Objective Lens 268
6. Stages and Cartridges 268
 - 6.1. Basic Cartridges 269
 - 6.2. Beryllium Cartridges 269
 - 6.3. Cold Stage 270
 - 6.4. Cryo-Transfer System 271
7. The HB501 271
 - 7.1. General Development 271
 - 7.2. HB501UX and High-Resolution Imaging 273
8. Special and Variant Instruments 273
 - 8.1. University of Glasgow's HB5 275
 - 8.2. The HB501A 276
9. The HB601 278

10. Postscript 280
- Acknowledgments 282
- References 283

7. Development of the 300-kV Vacuum Generator STEM (1985–1996)

287

H. S. von Harrach

1. Prelude in Oxford (1973–1975) 288
2. The MIDAS Project (1985–1988) 288
 - 2.1. System 289
 - 2.2. Gun Lens 289
 - 2.3. Objective Lens 290
 - 2.4. Side-Entry Stage 291
 - 2.5. MIDAS Performance 291
3. The HB603 300-kV STEM instruments 292
 - 3.1. The Prototype Design Phase 293
4. MIT and ANL Designs 305
5. Oak Ridge Design 307
6. Lehigh Design 310
7. Testing, Testing 311
8. Record-Breaking Results 316
 - 8.1. Source Brightness 316
 - 8.2. Energy Spread 316
 - 8.3. ADF Resolution 316
 - 8.4. X-Ray Microanalysis 317
9. Conclusions 320
- Acknowledgments 321
- References 322

8. On the High-Voltage STEM Project in Toulouse (MEBATH)

325

Bernard Jouffrey

1. Introduction 325
2. The Building 328
3. Generator 333
4. The Column 336
 - 4.1. The Source 336
 - 4.2. Accelerating Tube 342
 - 4.3. Lenses 346
 - 4.4. Spectrometers 348
5. Suspension of the Platform and the Microscope 349
6. Recording of The Signal 351
7. Conclusions 352
- Acknowledgments 352
- References 353

9. Scanning Transmission Electron Microscopy: Biological Applications

357

Andreas Engel

1. Introduction 358
2. Image Formation 359
 - 2.1. Electron-Sample Interactions 359
 - 2.2. The Optical System 360
 - 2.3. Detectors 360
 - 2.4. Single-Electron Counting 361
 - 2.5. Imaging Modes 363
3. Imaging Thin Sections 363
4. Imaging Negatively Stained Samples 365
5. Mass Measurements Using the Basel STEM 366
 - 5.1. Principle 366
 - 5.2. Estimate of the Statistical Error 369
 - 5.3. Mass Determination of Biological Samples 371
6. Specific Examples of STEM Imaging and Mass Measurements 373
7. High-Throughput Visual Proteomics 378
8. Conclusions and Perspectives 380
- Acknowledgments 382
- References 382

10. STEM at Cambridge University: Reminiscences and Reflections from the 1950s and 1960s

387

K. C. A. Smith

1. STEM as a Diagnostic Tool for SEM 387
2. The Observation of Specimens in Water Vapor by Means of STEM 391
3. High-Voltage STEM Using a Single-Field Condenser—Objective Lens 400
- References 401

Contents of Volumes 151–158

407

Index

411